

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet

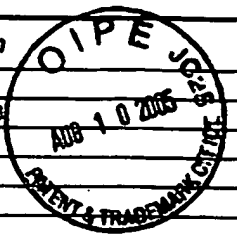
1

of

1

Complete if Known

Application Number	10/721,903
Filing Date	November 26, 2003
First Named Inventor	Nobuhiko Komine
Art Unit	2851
Examiner Name	D. Rutledge
Attorney Docket Number	3180.0342

**U.S. PATENTS AND PUBLISHED U.S. PATENT APPLICATIONS**

Examiner Initials	Cite No. ¹	Document Number	Issue or Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US-			
		US-			
		US-			
		US-			
		US-			
		US-			
		US-			
		US-			

Note: Submission of copies of U.S. Patents and published U.S. Patent Applications is not required.**FOREIGN PATENT DOCUMENTS**

Examiner Initials	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Translation ⁹
		Country Code ³ Number ⁴ Kind Code ⁶ (if known)				
D.R.		JP 2001-319871	11/16/01	Nikon Corp.		Abstract
D.R.		JP 2000-310850	11/7/00	Toshiba Corp.		Abstract

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation ⁹
D.R.		Notice of Grounds for Rejection, issued by the Japanese Patent Office, mailed June 21, 2005, in Japanese Patent Application Serial No. P2002-342798, and English-language translation thereof	
D.R.		DIRKSEN et al., "Focus and exposure dose determination using stepper alignment," SPIE (1996), 2726:799-808	
D.R.		STARIKOV, "Exposure Monitor Structure," SPIE (1990), 1261:315-324	

Examiner Signature		Date Considered	11/5/05
-----------------------	--	--------------------	---------

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.